

Notice of References Cited	Application/Control No. 10/008,623	Applicant(s)/Patent Under Reexamination SCHULER ET AL.	
	Examiner Alexander Markoff	Art Unit 1746	Page 1 of 1

U.S. PATENT DOCUMENTS

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	A	US-6,085,764	07-2000	Kobayashi et al.	134/147
	B	US-5,849,091	12-1998	Skrovan et al.	134/1
	C	US-6,048,405	04-2000	Skrovan et al.	134/1
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	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

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NON-PATENT DOCUMENTS

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	U	Handbook of Semiconductor Wafer Cleaning Technology, Noyes Publications, pages 141 and 142, 1993.
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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